



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of: **Kenji WATANABE et al.**

Art Unit: **2881**

Application Number: **10/543,151**

Examiner: **Kiet Tuan Nguyen**

Filed: **April 18, 2006**

Confirmation Number: **2634**

For: **MAPPING-PROJECTION-TYPE ELECTRON BEAM APPARATUS FOR  
INSPECTING SAMPLE BY USING ELECTRONS EMITTED FROM THE  
SAMPLE**

Attorney Docket Number: **052886**  
Customer Number: **38834**

**INFORMATION DISCLOSURE STATEMENT**  
**UNDER 37 C.F.R. §1.97(b)**

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

April 23, 2009

Sir:

In compliance with 37 C.F.R. §1.56, Applicants direct the attention of the Patent and Trademark Office to the documents listed on the attached PTO/SB/08. This paper is being filed within the time periods set forth in 37 C.F.R. §1.97(b). A copy of each non-U.S. document is enclosed herewith.

The documents are cited in the International Search Report of the corresponding international application.

If there are any fees due in connection with the filing of this paper, please charge Deposit Account No. 50-2866.

Respectfully submitted,

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Enclosures: PTO/SB/08  
7 Document(s)  
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